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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:) Examiner: Unknown
)
FISCHER et al.)
) Art Unit: 2817
Application No. 10/077,072)
) Docket No. P0877
Filed: February 14, 2002)
) Date: April 8, 2002
For: A Plasma Processing Apparatus)
And Method for Confining An RF Plasma)
Under Very High Gas Flow and RF Power)
Density Conditions (As Amended))
)
_____)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231 on April 8, 2002.

Signed: Sharon D. Tillery
Sharon D. Tillery

Preliminary Amendment

Commissioner for Patents
Box Non-Fee Amendment
Washington, DC 20231

✓ Sir:

Please enter the following preliminary amendment prior to examining the above referenced patent application.

IN THE TITLE

Please change the title from "A Plasma Processing Apparatus and Method" to
--A Plasma Processing Apparatus and Method for Confining an RF Plasma Under
Very High Gas Flow and RF Power Density Conditions--